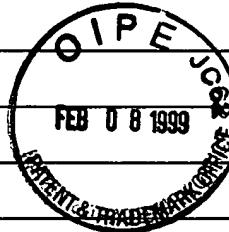


U.S. Department of Commerce, Patent and Trademark Office		Docket No.	Serial No.
		APPM/3049	09/206,027
LIST OF RELEVANT ART CITED BY APPLICANT (Use several sheets if necessary)		Applicant	
		Cohen, et al.	
		Filing Date	Group
		December 4, 1998	Unknown



#### U.S. Patent Documents

*Examiner Initial		Document Number	Issue Date	Name	Class	Subclass	Filing Date If Appropriate
LV	AA	5,660,682	08/26/1997	Zhao, et al.	638	715	
	AB						
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	AD						
	AE						
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	AG						
	AH						RECEIVED
	AI						FEB 16 1999
	AJ						GROUP 2100
	AK						

#### Foreign Patent Documents

Translation

		Document Number	Date	Country	Class	Subclass	Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							

#### OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

AQ	
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Examiner LAN VINH	Date Considered 2/11/2000
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		Document Number	Date	Country	Class	Subclass	Yes	No
	AL						RECEIVED	
	AM						MAP 24 1999	
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	AP							

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LV	AQ	Yasushi Sawada, Hiroshi Tamaru, Masuhiro Kogoma, Motoaki Kawase, and Kenji Hashimoto, "The Reduction of Copper Oxide Thin Films With Hydrogen Plasma Generated By An Atmospheric-Pressure Glow Discharge," J. Phys. D: Appl. Phys. 29 (1996), pp. 2539-2544.
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2/11/2000

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